

ABSTRACT OF THE DISCLOSURE

The present invention provides a sputtering target for production of a magnetic recording medium including
5 at least a nonmagnetic undercoat layer, a magnetic layer, and a protective layer laminated sequentially on a nonmagnetic substrate, the sputtering target being used for film formation of the magnetic layer, the sputtering target comprising a mixture of a metal and an oxide, and
10 the particle diameter of the oxide in the sputtering target being 10 μm or less. The sputtering target suppresses abnormal discharge occurring during film formation of a granular magnetic layer of the magnetic recording medium, and suppresses occurrence of foreign objects on the
15 magnetic recording medium.